



Japan TC Chapter of Information & Control Global Technical Committee Liaison Report

As of March 31, 2016

Ver.1.0

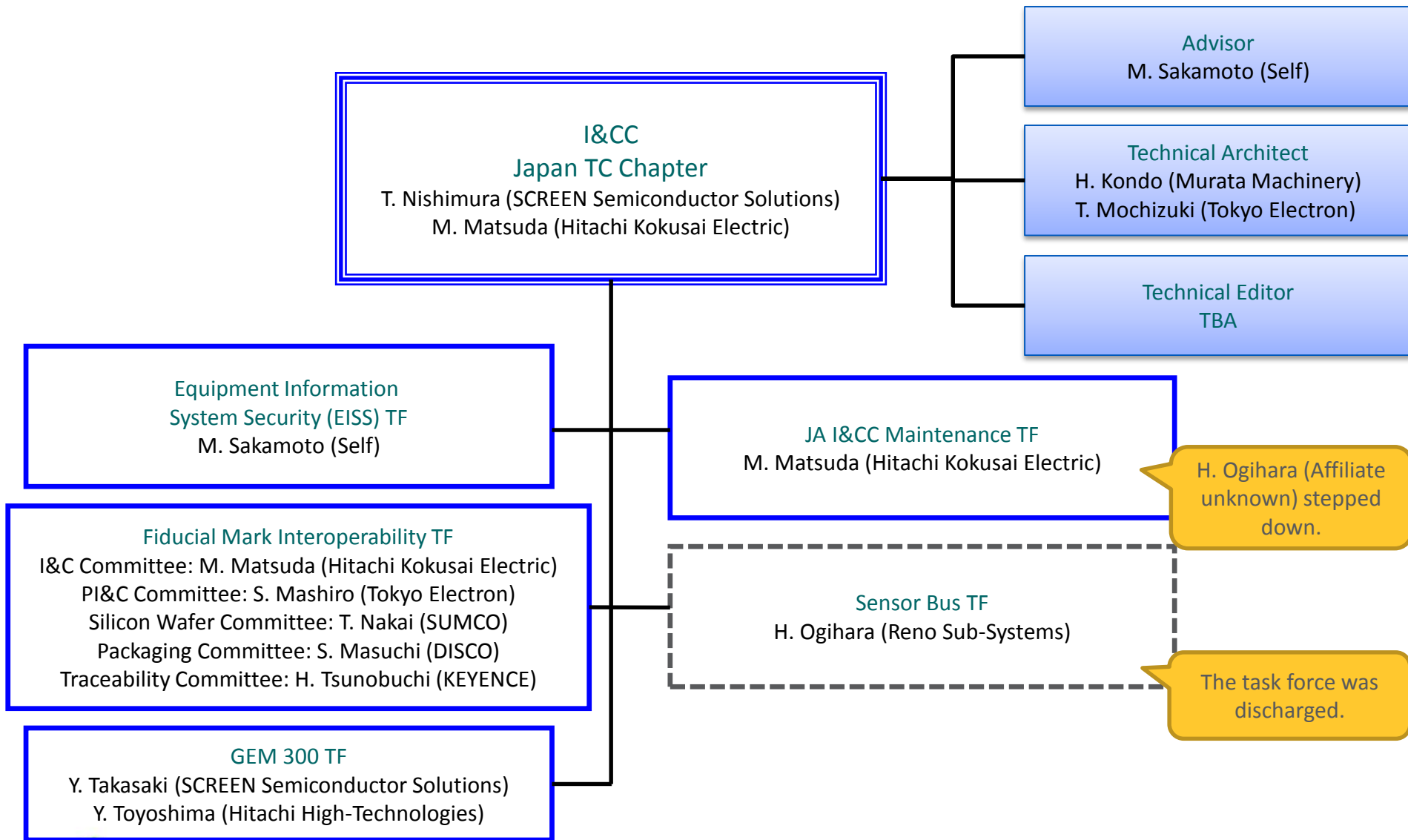
Outline

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- Current I&CC Japan TC Chapter Structure
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I&CC Japan TC Chapter Leadership

- Co-chairs
 - Takayuki Nishimura / SCREEN Semiconductor Solutions
 - Mitsuhiro Matsuda / Hitachi Kokusai Electric
- Advisor
 - Mitch Sakamoto / Self
- Technical Architect
 - Hiroshi Kondo / Murata Machinery
 - Tadashi Mochizuki / Tokyo Electron
- Technical Editor
 - TBA

Current I&CC Japan TC Chapter Structure



Document Review Summary at Japan Standards Fall 2015 Meetings

Cycle 6 –2015		
Doc #	Description	Japan Chapter Action
5829	Line-item Revision to SEMI E171-0515 “SPECIFICATION FOR PREDICTIVE CARRIER LOGISTICS (PCL)” and SEMI E171.1-0515 “SPECIFICATION FOR SECS-II PROTOCOL FOR PREDICTIVE CARRIER LOGISTICS”	
LI 1	Correct editorial errors in Table 24 ‘CLJ State Transition Table’	Passed as balloted
LI 2	Correct editorial errors in Table 16 ‘CFJ State Transition Table’	Passed as balloted
LI 3	Improve expression of CFJ Event definition	Failed and returned to TF for rework
LI 4	Improve CLJ Event definition	Failed and returned to TF for rework
LI 5	Correct Table A2-1 ‘Transitions and States’	Passed as balloted Superclean
LI 6	Align mnemonics used in E171.1 to E171	Passed as balloted
LI 7	Remove ObjType of CLJ from CFJ Event parameters	Passed as balloted

*Doc. #5829 had been published as SEMI E171-1215 and SEMI E171.1-1215.

Document Review Summary at Japan Standards Winter 2015 Meetings in conjunction with SEMICON Japan 2015

Cycle 8 –2015		
Doc #	Description	Japan Chapter Action
5829A	Line-item Revision to SEMI E171-0515 “SPECIFICATION FOR PREDICTIVE CARRIER LOGISTICS (PCL)” and SEMI E171.1-0515 “SPECIFICATION FOR SECS-II PROTOCOL FOR PREDICTIVE CARRIER LOGISTICS”	
LI 1	Improve expression of CFJ Event definition	Passed as balloted
LI 2	Improve CLJ Event definition	Passed as balloted
LI 3	Add ‘Object’ to the reference in the section 8.1.1 of E171	Passed as balloted
LI 4	Correct editorial errors in Table 14 and Table 16 of E171	Passed as balloted
LI 5	Add CarrierFlowID and CLJLPID to Table 8 CLJ SECS-II Attribute Definitions of E171.1	Passed as balloted
LI 6	Improve definition of the response to AMHSArrivalInfo service in E171	Passed as balloted
5888	Revision to E170 with title changes to “SPECIFICATION FOR SECURED FOUNDATION OF RECIPE MANAGEMENT SYSTEM (SFORMS)”, and E170.1 to “SPECIFICATION FOR SECS-II PROTOCOL FOR SECURED FOUNDATION OF RECIPE MANAGEMENT SYSTEM (SFORMS)”	Passed with editorial changes

*Doc. #5829A had been published as SEMI E171-0216 and SEMI E171.1-0216.

**Doc. 5888 passed at A&R and waiting for Proof.

Document Review Summary at Japan Standards Spring 2016 Meetings

Cycle 1 –2016		
Doc #	Description	Japan Chapter Action
5829B	Line Item Revision to SEMI E171-0515 “Specification for Predictive Carrier Logistics (PCL)”	
LI 1	Rename old mnemonics left nonreplaced in Figure 9, Figure 10, Figure A1-1, Figure A1-4, Figure A1-7, Figure A2-3, and Figure A2-4 to new ones	Passed as balloted
LI 2	Rename old mnemonics left nonreplaced in Figure A1-3, Figure A1-6, and Figure A1-9 to new ones, and add columns for CLJ attributes ‘URPState’ and/or ‘LSPState’ as needed to make the table more understandable	Passed as balloted Superclean

Approved SNARF revision by GCS on October 14, 2015

Doc #	Description	TF
5601	New Standard: SPECIFICATION FOR WAFER JOB MANAGEMENT (WJM)	GEM300 TF

The TC Chapter granted a one-year extension of the project period for the SNARF for the New Standard: “Specification for Wafer Job Management (WJM)” (to June 18, 2017).

Approved SNARF at Japan Standards Winter 2015 Meetings in conjunction with SEMICON Japan 2015

Doc #	Description	TF
5973	SNARF for Line Item Revision to SEMI E170-mm16 (SEMI Doc. #5888) "SPECIFICATION FOR SECURED FOUNDATION OF RECIPE MANAGEMENT SYSTEM (SFORMS)" and SEMI E170.1-mm16 (SEMI Doc. #5888) "SPECIFICATION FOR SECS-II PROTOCOL FOR SECURED FOUNDATION OF RECIPE MANAGEMENT SYSTEM"	GEM300 TF

Approved Revised SNARF

Japan Standards Winter 2015 Meetings

in conjunction with SEMICON Japan 2015

Doc #	Description	TF
5829	Line Item Revision to SEMI E171-0515 "SPECIFICATION FOR PREDICTIVE CARRIER LOGISTICS (PCL)"	GEM300 TF

After the revision to SNARF #5829 was approved Ballot 5829B was submitted for Cycle 1–2016 and passed at the Japan TC Chapter meeting on March 8, 2016.

Ballots to be reviewed at Japan Standards Summer 2016 Meetings

Cycle 4/5/6 - 2016		
Doc #	Description	TF
5601A	New Standard: SPECIFICATION FOR WAFER JOB MANAGEMENT (WJM)	GEM300 TF

Task Force Updates [1/6]

- Equipment Information System Security (EISS) TF
 - Presented SEMI E169 in KSIA/SEMI Korea I&C Workshop
 - Wed. 24th April, 2016, in Seoul
 - Around 50 people attended
 - EISS, ESEC and Backend Process were in the agenda
 - Access control with RBAC (Role Based Access Control) was discussed.
 - Drafting Two SNARFs
 - SNARF for Specification for Authentication Data Transfer
 - SNARF for Specification for Role Based Access Control
 - Patent application relevant to the RBAC (TEL)
 - Next TF meeting
 - To be held on Wednesday, April 13 , 10 a.m. to 12 a.m. at SEMI Japan office.

Task Force Updates [2/6]

- Fiducial Mark Interoperability TF
 - The latest TF meeting on Nov. 18, 2015
 - T7 issues
 - SNARF 5890
 - Delete all position specifications from SEMI T7 because position specifications are also described on SEMI M1 and other related Silicon Standard.
 - Document 5890
 - Submitting to 2015 Cycle 7, passed with editorial changes at JA TC Chapter meeting of Traceability TC on Dec. 18, 2015, and passed A&R.
 - Waiting for publication.
 - Others
 - Assembly and Packaging: Discussing backend alignment issues with introducing fiducial mark wafer.
 - TF leaders to start discussion about disbanding this TF if the TF doesn't have further activity.

Task Force Updates [3/6]

- GEM 300 TF
 - #5829A, Line Item Revision to SEMI E171 & SEMI E171.1 (PCL)
 - All six line items were passed as balloted at I&C Japan TC Chapter meeting in conjunction with SEMICON Japan 2015 on December 18.
 - Published as SEMI E171-0216 and E171.1-0216.
 - #5829B, Line Item Revision to SEMI E171 (PCL)
 - Revised SNARF #5829 for revision to E171 PCL was approved at I&C Japan TC Chapter meeting in conjunction with SEMICON Japan 2015 on December 18.
 - To correct mnemonics in some figures
 - Two line items were passed as balloted at I&C Japan TC Chapter meeting on March 8.
 - To be reviewed at A&R.

Task Force Updates [4/6]

- GEM 300 TF (cont' d)
 - #5888, Revision to SEMI E170 & SEMI E170.1 (PRC to SFORMS)
 - Ballot was passed with editorial changes at I&C Japan TC Chapter meeting in conjunction with SEMICON Japan 2015 on December 18.
 - Passed at A&R and waiting for Proof.
 - #5973: Line Item Revision to SEMI E170 & SEMI E170.1
 - SNARF was approved at I&C Japan TC Chapter meeting in conjunction with SEMICON Japan 2015 on December 18.
 - It is highly probable that documentation quality issues
 - #5601: New Standards for “Wafer Job Management”
 - Approved Change concept “Wafer Object” to “Wafer Job”
 - Revised SNARF was approved by GCS on October 14, 2015.
 - The TC Chapter granted a one-year extension of the project period for the SNARF (to June 18, 2017).
 - #5601A Ballot submission for Cycle 4/5/6 was approved at I&C Japan TC Chapter meeting on March 8.
 - JA GEM300TF member agreed to name SEMI E170, SEMI E171 and 5601 document group as ‘GEM300A ‘.

Task Force Updates [5/6]

- JA I&CC Maintenance
 - Leadership change
 - Hideaki Ogihara (Affiliate unknown) stepped down.
 - #5615: Revision to E98&E98.1 (OBEM)
 - To remove “provisional”. Work in progress.
 - SEMI E153 (AMHS SEM)
 - Technical revision is not required by review
 - Pending reapproval due to SML notation issues.
 - SEMI E99 (Carrier ID Reader/Writer)
 - Maintenance TF is assigned for this revision activity.
 - SNARF to be prepared.
 - Work in progress to list up items to revise.
 - The activity of SEMI E107 “Specification of Electric Failure Link Data Format for Yield Management System”
 - Ogiwara-san is in charge to decide the next action. (Revision / INACTIVE / ...)
 - SEMI E91 (PSEM)
 - SNARF to be prepared

Task Force Updates [6/6]

- Sensor Bus TF
 - The TC Chapter approved to discharge the task force at the TC Chapter meeting on March 8.
 - Japan I&C Maintenance TF will take care of their documents developed by Sensor Bus TF.

Announcement

- GEM300A
 - SEMI E170, SEMI E171 and #5601 document group was named “GEM300A”.
- STEP/GEM300A
 - To be held on Friday, May 20, 13:00–18:00, at SEMI Japan office
 - Covers SEMI E170 and SEMI E171
 - To be hosted by I&C Japan TC Chapter
 - Co-chairs
 - Takayuki Nishimura (SCREEN) and Mitsuhiro Matsuda (Hitachi Kokusai Electric)
 - Speakers
 - Koji Kitajima and Syoichi Harakawa (Toshiba)
 - Yoshihisa Takasaki (SCREEN)
 - Yuko Toyoshima (Hitachi High Technologies)

Meeting Information – Japan TC

- Last Meeting – Japan Spring 2016 Meetings:
 - Tuesday, March 8, 2016 1:30PM–5:00PM
 - @ SEMI Japan Office, Tokyo, Japan
- Next Meeting – Japan Summer 2016 Meetings:
 - Thursday, June 16, 2016 1:30PM–5:00PM
 - @ SEMI Japan Office, Tokyo, Japan

Schedule for I&CC Japan TC Chapter Meetings

- Summer in June 16, 2016
- Fall in September 2016
- Winter in December 16, 2016 (tentative)
 - in conjunction with SEMICON Japan 2016
- Spring in April, 2017

*End of
I&CC Japan TC Chapter
Liaison Report
Thank You!*

*For more information, please contact
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